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11-20-03

PATENT
Customer No. 22,852
Attorney Docket No. 04329.2409

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kei YOSHIKAWA et al.

Application No.: 09/662,219

Filed: September 14, 2000

For: PATTERN CORRECTING METHOD
OF MASK FOR MANUFACTURING A
SEMICONDUCTOR DEVICE AND
RECORDING MEDIUM HAVING
RECORDED ITS PATTERN
CORRECTING METHOD

)
)
) Group Art Unit: 2623
)
) Examiner: S. Ahmed
)
)

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Technology Center 2600

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

PETITION FOR EXTENSION OF TIME

Applicants hereby petition for a one-month extension of time to reply to the Office
Action of July 14, 2003. A fee of \$110.00 is enclosed.

Please grant any extensions of time required to enter this response and charge
any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

By: 

D. Kent Stier
Reg. No. 50,640
(404) 653-6559

Dated: November 6, 2003

11/07/2003 AOSMAH1

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